

Low-pressure plasma system

V55-GKM

The highly flexible standard device

The unit is integrated in a 19" rack, which is equipped with rollers and height-adjustable feet. For easy loading the system can be equipped either with a swing door or a sliding door (automatable as an option).

The system can be used for the surface treatment methods cleaning, activation, etching and coating.

Technical data

Outer dimensions: approx. W 620 x H 1,850 x D 900 mm

Inner dimensions process chamber: approx. W 400 x H 340 x D 460 mm

Microwave power generator: 2.45 GHz, from 100 W up to max. 1,200 W

Gas supply: 2 gas channels with mass flow controllers and magnetic valves

Vacuum connection: DN 40 ISO-KF

Electrical connection: 230/400 V, 50/60 Hz, 2.2 kW, 16 A (without vacuum pump)

Process control: PLC control unit (PP 420 by B & R)

Vacuum gauge: capacitance manometer (independent of gas type)

Printer: 8-pin standard paper printer

Available Options

- Vacuum pump
- Ozone trap
- Further gas channels (up to max. 4)
- kHz generator (40 kHz)
- MHz generator (13,56 MHz)
- Rotating drum for bulk material treatment
- Rotating table
- Ethernet interface
- Exhaust gas scrubber
- Automatical door opening and closing (sliding door version)
- Liquiflow controller
- Chamber liner
- Soft-start and slow-vent
- Further options on request

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The variable standard system V55-GKM has a high process operating flexibility because of its two gas channels and three optional plasma generating frequencies.